


INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 005918 USA/FPS/MMCS/APC		SERIAL NO. 09/943 955 RECEIVED DEC 19 2003 Technology Center 2100	
				APPLICANT SHANMUGASUNDRAM et al.			
				FILING DATE August 31, 2001		GROUP 2122	
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
L.T.M-E	4,207,520	06/10/80	Flora et al.	324	238	04/06/78	
L.T.M-E	4,209,744	06/24/80	Gerasimov et al.	324	241	03/27/78	
L.T.M-E	4,609,870	09/02/86	Lale et al.	324	225	09/13/84	
L.T.M-E	4,755,753	07/05/88	Chern	324	237	07/23/86	
L.T.M-E	5,427,878	06/27/95	Corliss	430	30	05/16/94	
L.T.M-E	5,534,289	07/09/96	Bilder et al.	427	8	01/03/95	
L.T.M-E	5,867,389	02/02/99	Hamada et al.	700	121	11/26/96	
L.T.M-E	6,041,263	03/21/00	Boston et al.	700	32	10/01/97	
L.T.M-E	6,077,412	06/20/00	Ting et al.	205	143	10/30/98	
L.T.M-E	6,271,670	08/07/01	Caffey	324	642	02/08/99	
L.T.M-E	6,400,162	06/04/02	Mallory et al.	324	688	07/21/00	
L.T.M-E	US 2002/0077031	06/20/02	Johansson et al.	451	6	07/06/01	
L.T.M-E	6,442,496	08/27/02	Pasady et al.	702	83	08/08/00	
L.T.M-E	6,563,308	05/13/03	Nagano et al.	324	230	03/27/01	
L.T.M-E	6,587,744	07/01/03	Stoddard et al.	700	121	06/20/00	
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
L.T.M-E	WO 01/11679	02/15/01	WIPO	—	—	X	
L.T.M-E	WO 01/080306	10/25/01	WIPO	—	—	X	
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
L.T.M-E	Miller, G. L., D. A. H. Robinson, and J. D. Wiley. July 1976. "Contactless measurement of semiconductor conductivity by radio frequency-free-carrier power absorption." <i>Rev. Sci. Instrum.</i> , Volume 47, No. 7. pp. 799 - 805.						
L.T.M-E	1999. "Contactless Bulk Resistivity/Sheet Resistance Measurement and Mapping Systems." www.Lehighton.com/fabtech1/index.html .						
L.T.M-E	2000. "Microsense II Capacitance Gaging System." www.adetech.com .						
EXAMINER <i>Lynette T. Umeg-Eumini</i>				DATE CONSIDERED <i>5/2/2004</i>			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 005918 USA/FPS/MMCS/APC		SERIAL NO. 09/943,955 RECEIVED DEC 19 2003 Technology Center 2100					
				APPLICANT SHANMUGASUNDRAM et al.				FILING DATE August 31, 2001		GROUP 2122	
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation					
						Yes	No				
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)											
L.J.M.-E.	El Chemali, Chadi et al. July/August 2000. "Multizone uniformity control of a chemical mechanical polishing process utilizing a pre- and postmeasurement strategy." <i>J. Vac. Sci. Technol.</i> Volume 18, No. 4. pp. 1287 - 1296.										
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L.J.M.-E.	2002. "Microsense II - 5810: Non-Contact Capacitance Gaging Module." www.adetech.com .										
L.J.M.-E.	08 August 2003. PCT International Search Report from PCT/US03/08513.										
L.J.M.-E.	14 October 2003. PCT International Search Report from PCT/US02/21942.										
L.J.M.-E.	20 October 2003. PCT International Search Report from PCT/US02/19116.										
L.J.M.-E.	23 October 2003. PCT International Preliminary Examination Report from PCT/US01/24910.										
L.J.M.-E.	"NanoMapper wafer nanotopography measurement by ADE Phase Shift." http://www.phase-shift.com/nanomap.shtml .										
L.J.M.-E.	"Wafer flatness measurement of advanced wafers." http://www.phase-shift.com/wafer-flatness.shtml .										
L.J.M.-E.	"ADE Technologies, Inc. - 6360." http://www.adetech.com/6360.shtml .										
L.J.M.-E.	"3D optical profilometer MicroXAM by ADE Phase Shift." http://www.phase-shift.com/microxam.shtml .										
L.J.M.-E.	"NanoMapper FA factory automation wafer nanotopography measurement." http://www.phase-shift.com/nanomapperfa.shtml .										
EXAMINER <i>Lynette J. Umeg-Euruni</i>				DATE CONSIDERED 5/2/2004							

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